

IN THE CLAIMS:

Cancel claims 10-20 as shown in the following listing of claims, which replaces all previous listings and versions of claims.

1.- 20. (canceled)

21. (previously presented) A method of correcting a redundant defect in a mask using a composite charged particle beam device, comprising the steps of:

providing a composite charged particle beam device having a focused ion beam lens barrel for producing a focused ion beam and an electron beam lens barrel for producing an electron beam;

scanning an electron beam produced by the electron beam lens barrel over a mask having a redundant defect to acquire an image of the mask;

identifying the position of the redundant defect from the image;

carrying out coarse correction of the redundant defect by etching using a focused ion beam produced by the focused ion beam lens barrel; and

carrying out finishing correction of the coarsely corrected redundant defect by etching using an electron beam produced by the electron beam lens barrel.

22. (previously presented) A method of correcting according to claim 21; wherein the finishing correction is carried out while directing an etching assist gas to the coarsely corrected redundant defect being irradiated by the electron beam.

23. (previously presented) A method of correcting according to claim 21; wherein the redundant defect is an opaque defect; the coarse correction is carried out to completely remove the opaque defect while incidentally injecting ions of the focused ion beam into the mask; and the finishing correction is carried out to remove the injected ions from the mask.

24. (previously presented) A method of correcting according to claim 21; wherein the focused ion beam is comprised of gallium ions.

25. (previously presented) A method of correcting according to claim 21; further including the steps of detecting secondary ions generated during coarse correction of the redundant defect and, when the type of detected secondary ions changes, terminating the coarse correction.

26. (previously presented) A method of correcting according to claim 21; further including the steps of detecting secondary ions generated during coarse correction of the redundant defect and, when the type of detected secondary ions changes, terminating the coarse correction and automatically switching to finishing correction to repair damage to the mask that occurred during coarse correction.